

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Chen, *et al.* Docket No.: TSM6283131RI
Serial No.: 10/650,886 Art Unit: 1763
Filed: August 28, 2003 Examiner: George A. Goudreau
For: In-Situ Strip Process for Polysilicon Etching in Deep Sub-Micron
Technology

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir:

The following remarks are offered in response to Examiner's Office Action dated June 15, 2006 and further pursuant to the telephonic discussion of September 13, 2006.